

1_TiO2_dep					
SUBROUTINE	STEPS				
Ignite	Ignite_HiV_00_Asst	Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam at step=shutoff	Beam at step=ExtractBeam		
		Beam at end=shutoff	Beam at end=PlasmaOnly		
		PBN=off	PBN=on		
		Beam voltage=0	Beam voltage=900	PM1	Process time
		Beam current=0	Beam current=160	Ti	20sec
		Ignition RF Power=0	Ignition RF Power=150		
		Suppressor Voltage=0	Suppressor Voltage=180		
		PBN Flowrate=5	PBN Flowrate=5		Shutter "at beam"
		K Factor=0	K Factor=3.1		substrate=close
		Gas Values	Gas Values	Target angle=55	target=close
		PM1	PM1		
		Ar=10	Ar=10		
		Xe=0	O2=0		
		N2=0	N2=0		
Ignite_HiV_01_DepoAsst					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam at step=ExtractBeam	Beam at step=ExtractBeam		
		Beam at end=ExtractBeam	Beam at end=ExtractBeam		
		PBN=on	PBN=on		
		Beam voltage=1120	Beam voltage=900	PM1	Process time
		Beam current=200	Beam current=200	Ti	20sec
		Ignition RF Power=150	Ignition RF Power=150		
		Suppressor Voltage=150	Suppressor Voltage=180		Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5		substrate=close
		K Factor=3.1	K Factor=3.1		target=close
		Gas Values	Gas Values	Target angle=55	
		PM1	PM1		
		Ar=10	Ar=10		
		Xe=0	O2=0		
		N2=0	N2=0		
Ignite_GridClean					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process
		Beam at step=ExtractBeam	Beam at step=ExtractBeam		
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly		
		PBN=on	PBN=on		
		Beam voltage=50	Beam voltage=50	PM1	Process time
		Beam current=310	Beam current=310	Ti	300sec
		Ignition RF Power=250	Ignition RF Power=250		
		Suppressor Voltage=800	Suppressor Voltage=800		Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5		substrate=close
		K Factor=2	K Factor=2		target=close
		Gas Values	Gas Values	Trget angle=55	
		PM1	PM1		
		Ar=10	Ar=10		
		Xe=0	Xe=0		
		N2=0	N2=0		

Warmup	Warm up	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=50	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	10sec	Fixture Rotation Speed=10rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=800	Suppressor Voltage=795			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	O2=0			
		N2=0	N2=0			
TiO2_GasRamp	TiO2_GasRamp	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	15sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=795			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=5	Ar=5			
		Xe=5	O2=5			
		N2=0	N2=0			
TiO2_PrepSputt	TiO2_PreDep1_Gas Stab.	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	60sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
	TiO2_PreDep2_Sputter	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	300sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			

		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
TiO2_Dep	TiO2_Dep					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=ExtractOnly	Beam at step=ExtractOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=1120	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	1800sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=800			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=open
		K Factor=2	K Factor=2			target=open
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=5	O2=20			
		N2=0	N2=0			
TiO2_GasRamp	TiO2_GasRamp					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=PlasmaOnly	Beam at step=PlasmaOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Do not change RF	Do not change RF			
		Beam voltage=1120	Beam voltage=55	PM1	Process time	Fixture Tilt Angle=40
		Beam current=380	Beam current=400	Ti	15sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=300	Ignition RF Power=300			
		Suppressor Voltage=180	Suppressor Voltage=795			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=5	Ar=5			
		Xe=5	O2=5			
		N2=0	N2=0			
TiO2_GridClean	SiO2_GridClean					
		Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=ExtractOnly	Beam at step=ExtractOnly			
		Beam at end=PlasmaOnly	Beam at end=PlasmaOnly			
		PBN=on	PBN=on			
		Beam voltage=50	Beam voltage=50	PM1	Process time	Fixture Tilt Angle=40
		Beam current=310	Beam current=310	Ti	300sec	Fixture Rotation Speed=20rpm
		Ignition RF Power=375	Ignition RF Power=375			
		Suppressor Voltage=800	Suppressor Voltage=800			Shutter "at beam"
		PBN Flowrate=5	PBN Flowrate=5			substrate=close
		K Factor=2	K Factor=2			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=10	Ar=10			
		Xe=0	Xe=0			
		N2=0	N2=0			

Shut_n_pmp_dv	Shut_n_pmp_dwn	Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=40
		Beam current=0	Beam current=0	Ti	30sec	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			Shutter "at beam"
		PBN Flowrate=0	PBN Flowrate=0			substrate=close
		K Factor=0	K Factor=0			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			
Shut_dwn_open_cryo						
		Depo Beam Parameters	Assist Beam Parameters	Target	Process	Fixture
		Beam at step=shutoff	Beam at step=shutoff			
		Beam at end=shutoff	Beam at end=shutoff			
		PBN=off	PBN=off			
		Beam voltage=0	Beam voltage=0	PM1	Process time	Fixture Tilt Angle=90
		Beam current=0	Beam current=0	Ti	10sec	Fixture Rotation Speed=10rpm
		Ignition RF Power=0	Ignition RF Power=0			
		Suppressor Voltage=0	Suppressor Voltage=0			Shutter "at beam"
		PBN Flowrate=0	PBN Flowrate=0			substrate=close
		K Factor=0	K Factor=0			target=close
		Gas Values	Gas Values	Target angle=55		
		PM1	PM1			
		Ar=0	Ar=0			
		Xe=0	Xe=0			
		N2=0	N2=0			